

L Number	Hits	Search Text	DB	Time stamp
3	5	118/715-733.cols. and ((wafer substrate) with (carrier holder) with (attach\$3 secur\$3) with spindle)	USPAT; US-PGPUB	2003/06/09 09:05
4	330	118/715-733.cols. and ((wafer substrate) with (carrier holder) with (attach\$3 secur\$3))	USPAT; US-PGPUB	2003/06/09 09:09
10	62	118/715.cols. and ((wafer substrate) with (carrier holder) with (attach\$3 secur\$3))	USPAT; US-PGPUB	2003/06/09 09:09
-	343	118/715-733.cols. and ((liner shutter shield) with (cylinder cylindrical\$3))	USPAT; US-PGPUB	2003/06/09 08:43
-	271	118/715-733.cols. and ((liner shutter shield) with (cool\$3))	USPAT; US-PGPUB	2003/06/08 16:02
-	263	118/715-733.cols. and ((liner shutter shield) with (reactor chamber)) and applied.as.	USPAT; US-PGPUB	2003/06/08 16:07
-	39	118/715-733.cols. and ((liner shutter shield) with (reactor chamber) with (annular cylindrical\$ cylinder)) and applied.as.	USPAT; US-PGPUB	2003/06/08 16:15
-	174	(118/715-733.cols. and ((liner shutter shield) with (reactor chamber)) and applied.as.) not (118/715-733.cols. and ((liner shutter shield) with (reactor chamber) with (annular cylindrical\$ cylinder) and applied.as.))	USPAT; US-PGPUB	2003/06/08 16:25
-	12	(US-6197121-\$ or US-6201591-\$ or US-6219114-\$ or US-6138172-\$ or US-6138116-\$ or US-6131702-\$ or US-6051773-\$ or US-6131111-\$ or US-6149038-\$ or US-6211201-\$ or US-6164811-\$ or US-6142617-\$).did.	USPAT	2003/06/08 16:32
-	4	(US-6197121-\$ or US-6201591-\$ or US-6138172-\$ or US-6138116-\$ or US-6131702-\$ or US-6051773-\$ or US-6131111-\$ or US-6149038-\$ or US-6211201-\$ or US-6164811-\$ or US-6190677-\$).did.) and cool\$3	USPAT; US-PGPUB	2003/06/08 16:32
-	8	(US-6197121-\$ or US-6201591-\$ or US-6138172-\$ or US-6138116-\$ or US-6131702-\$ or US-6051773-\$ or US-6131111-\$ or US-6149038-\$ or US-6211201-\$ or US-6164811-\$ or US-6190677-\$).did.) and cool\$3	USPAT; US-PGPUB	2003/06/08 16:32
-	28	6388122.OPEN.	USPAT	2003/06/08 16:36
-	15	6388122.OPEN. and cool\$3	USPAT; US-PGPUB	2003/06/08 16:36
-	2	"6411162"	EPC; JPC; DEFWENT	2003/06/08 16:36
-	35747	((liner shutter shield) with (cool\$3 annular cylindrical\$ cylinder))	USPAT; US-PGPUB	2003/06/08 16:06
-	6284	c23c016\$.ipc.	USPAT; US-PGPUB	2003/06/08 16:07
-	53026	h111021\$.ipc.	USPAT; US-PGPUB	2003/06/08 16:07
-	5463	((deposit\$ etch\$ "cvd" layer film) same ((liner shutter shield) with (cool\$3 annular cylindrical\$ cylinder))	USPAT; US-PGPUB	2003/06/08 16:06
-	0	((c23c016\$.ipc. h111021\$.ipc.) and ((liner shutter shield) with (cool\$3 annular cylindrical\$ cylinder))	EPC; JPC; DEFWENT	2003/06/08 16:06
-	0	((c23c016\$.ipc. h111021\$.ipc.) and ((liner shutter shield) with (cool\$3) with (annular cylindrical\$ cylinder))	EPC; JPC; DEFWENT	2003/06/08 16:06
-	0	((c23c016\$.ipc. h111021\$.ipc.) and ((liner shutter shield) same (cool\$3) same (annular cylindrical\$ cylinder))	EPC; JPC; DEFWENT	2003/06/08 16:07
-	49231	c23c016\$.ipc.	EPC; JPC; DEFWENT	2003/06/08 16:07

-	742974	h011021\$.ipc.	EPO; JPO; DEFWENT	2003/06/08 18:08
-	34	(c23c016\$.ipc. h011021\$.ipc.) and ((liner shutter shield) same (cool\$3) same (annular cylindrical\$ cylinder))	EPO; JPO; DEFWENT	2003/06/08 16:07
-	0	200200059970.URPN.	USEPAT	2003/06/08 16:31
-	1	("611125").PN.	USEPAT; US-PGPUE	2003/06/08 17:26
-	1	("611125").PN.	USEPAT; US-PGPUE	2003/06/08 17:26
-	15	h011021\$.ipc. and (reactor with "stainless steel")	EPO; JPO; DEFWENT	2003/06/08 17:28
-	634	h011021\$.ipc. and ((multiple plural\$3) with (wafer substrate; with carrier)	EPO; JPO; DEFWENT	2003/06/08 18:10
-	84	118/718.ccls. and ((multiple plural\$3) with (wafer substrate; with holder)	USEPAT; US-PGPUE	2003/06/08 18:15
-	42	118/708.ccls. and ((multiple plural\$3) with (wafer substrate; with carrier)	USEPAT; US-PGPUE	2003/06/08 18:11
-	5	118/708.ccls. and ((multiple plural\$3) with (wafer substrate; with holder) and 118/719.ccls.	USEPAT; US-PGPUE	2003/06/08 18:16
-	84	((multiple plural\$3) with (wafer substrate) with holder) and 118/719.ccls.	USEPAT; US-PGPUE	2003/06/08 18:16
-	24	((multiple plural\$3) with (wafer substrate) with holder with (transfer\$4 transport\$3)) and 118/719.ccls.	USEPAT; US-PGPUE	2003/06/08 18:17
-	35	118/715-733.ccls. and ((wafer substrate) with (holder) with (secur\$3 attach\$3) with (spindle rotat\$3))	USEPAT; US-PGPUE	2003/06/08 18:30